Tool ID: 414
Tool Location: 121

Equipment Information Sheet

Gamma Automatic Coat-Develop Tool

Manager: Garry Bordonaro 607-254-4936
Backup: Daniel McCollister 607-254-8207
Backup: Giovanni Sartorello 607-254-4853

Calls to staff phones will be automatically forwarded to their cell phones during accessible hours. At other times leave a message or send them an email.

SAFETY

- Ensure the I/O Door interlock button is actuated before loading wafers. The system will not run if the front door is open.

USAGE RESTRICTIONS
SCHEDULING/SIGN-UP RESTRICTIONS

Minimum Tool Time: 15 minutes

- Please reserve time in CORAL
- While two processes can be run simultaneously, only one user is allowed to operate the system during their scheduled window.

MATERIALS COMPATIBILITY CATEGORY

Tool Category 5: Class A and B Metals and Compounds

Allowed	Not Allowed
Tool category 1/1E, 2, 3, and 4 materials	
Silicon Based Substrates and Films	
III/V compound Semiconductors	
Glass Substrates	
PECVD and ALD Films	
Cured organics and baked Photoresist	
CNF Class A, B, and Refractory metals	
Exposed Gold, Silver, Copper	
Alkali and Alkaline Compounds	
Organic/Biology Molecules prepared-w/salt buffers	
High Vapor Pressure Materials (Mg, Ca, Zn)*	* Some tool restrictions on high vapor pressure materials may apply
Soft organic materials	

High Vapor Pressure Metals and Compounds are materials that have a vapor pressure above 1e-6 Torr at 400 C.

Additional Material Restrictions and Exceptions

- 100mm wafers standard, up to 200mm compatible
- Other size wafers must be scheduled with the equipment owners
- NO warped wafers
- Backside of wafers must be free of contamination prior to placing in system

Last Updated: 01/22/2026